

coordinates are carried out with the aid of an automatic recording microphotometer (Rigaku-Denki MP-3). The profiles of the various ellipses of a family are traced along the major axis and the peak-to-peak distances of the profiles, measured with an accuracy of $\pm 5 \mu$, determine the end-points of the corresponding y_n coordinates.

The x_n coordinates are controlled by fixed precision spacers which define the discrete film positions and which span the range of specimen-to-film distance from 15 mm down to virtually zero. The size of the ellipses which can be recorded is limited by the dimensions of the film and the existence of a hole at its center. Therefore, the selection of the discrete film positions will be governed by considerations pertaining to the completion of the elliptical patterns. For large values of y_n some portions of the ellipses may fall outside the film area and consequently the selection of x_n will depend principally on crystal orientation, wavelength used, and lattice spacing of planes which are being measured.

To insure accurate determinations of the x_n coordinates it is necessary to satisfy two requirements: (1) the film should be perfectly flat and (2) the film surface should be maintained normal to the direction of its displacement. The first requirement was fulfilled by machining grooves in the backplate of the film cassette so that a vacuum could be applied. Only when the film had been flatly pressed to the backplate through the application of the vacuum was the clamping frame tightened. The second requirement is satisfied by accurate machining of the cassette. Special care must be taken in mating the cassette base with the spacers to reduce errors in the determination of the discrete film positions x_n .

It was observed that the precision of measurements of d spacings increases with decreasing α , that is, with increasing θ values. Consequently, it is highly desirable to record a great many complete ellipses in the vicinity of the center of the film. To minimize the interception of the diffracted x rays at small α values by the x-ray tube itself, a long, tapered tip was fitted to the tube. This tip may be described as a truncated cone having a conical angle of 7° , a circular tip surface of 0.16-cm (1/16-in.) diameter and a height of 4.45 cm (1.75 in.)

b. Photographic Technique

A number of precautions in photographic processing have to be taken to achieve a high degree of precision. It is, for example, absolutely imperative that the film shrinkage be uniform (isotropic) if the differences in spacings between various (hkl) reflections of a single crystal are to be utilized as a basis for a subsequent strain analysis. After long experimentation it was found that Pont Cronar base, single-coated, graphic arts film (X12 in.) satisfied the requirements for isotropic film shrinkage. Correction for film shrinkage is made by pressing a standard scale on the exposed film and measuring it after photographic processing.

In order to minimize film shrinkage and background scattering, and thereby produce maximum contrast, the following photographic processing practice was adopted. All the films were developed for 2 min in Kodak HC110 developer diluted 5:1, followed by fixing in Kodak x-ray fixer for 6 min. Washing for six minutes and then immersion in Photoflo solution for 30 sec was followed by natural drying of the film. In this way it was possible to reduce film shrinkage to a minimum and also to insure that any dimensional change was uniform over the whole film.

c. Computer Programming

A computer program was written to expedite the repeated computation of d spacings. The input to this program was: coordinates (x_i, y_i) , shrinkage factor, and wavelength used. The output was: d spacings and their corresponding standard errors.

In addition, a program was also written for the computation of the lattice parameter based on the method of weighted least squares. The input to this program was: d spacings, standard error of d spacings, and Miller indices of planes. The output was: the parameters of the weighted least-squares line and their associated standard errors. Mathematical details for the computation of the d spacings, lattice parameter, and respective errors are given in Appendix A.

The output of d -spacing computations was used for the computation of the stress-strain configuration of the strained crystals.^{1,2} Indeed, it is primarily for reasons of attaining the highest degree of precision in the stress-strain analysis of crystals that the precision measurements by the divergent beam method were developed here in such detail.

4. EFFECT OF HOMOGENEOUS AND INHOMOGENEOUS STRAINS ON THE PSEUDO-KOSSEL PATTERN

If the crystal is subjected to long-range elastic strains or to homogeneous internal strains (residual strains), the shape of the pseudo-Kossel lines will be significantly altered. The homogeneous strains are then manifested by changes in the length of the major axis of the elliptical patterns. These changes in turn affect the slope parameters m_1 and m_2 and consequently the strain fluctuation can be recorded in terms of the changes of the d spacings of various (hkl) planes. Thus, if the changes of d spacings of more than six independent (hkl) planes are recorded, the complete strain distribution of the crystal can be obtained.^{1,2} However, if the strains are inhomogeneous, then in addition to dimensional changes of the elliptical pattern local line broadening, kinking or displacement of line segments will occur. The effect of such strains on the pseudo-Kossel lines is shown in Fig. 4. From the schematic drawing of Fig. 1 it may be seen that adjacent areas on the specimen surface give rise to adjacent segments of